



INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(Use several sheets if necessary)

Attorney Docket No.:

8007-1111

Application No.:

10/583.942

Applicant:

Atsushi SAKURAI et al.

Filing Date:

June 22, 2006

Group Art Unit;

2812

U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

LEE et al., "Effect of the precursors on the deposition of (Ba,Sr)TiO₃ films," *J. Phys. IV France*, Vol. 11, 2001, pp. Pr3-215-222.

EXAMINER:

/Joel Horning/

DATE CONSIDERED

04/29/2009

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

BC:rk

Y&T February 7, 2007

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /J.H./